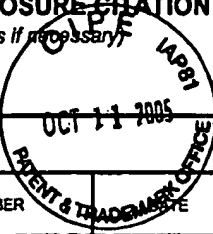


INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)				ATTY DOCKET NO.		APPLICATION NO.	
				YOR920030602US1 (17242)		10/725,850	
				APPLICANT(S)			
				Joel P. de Souza et al.			
				FILING DATE		GROUP ART UNIT	
				December 2, 2003		2818	




U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
dhu	5,384,473	01/24/1995	Yoshikawa et al.	1	1	1	
dhu	6,815,278 B1	11/09/2004	Icong et al.	1	1	1	

U.S. PATENT APPLICATION PUBLICATIONS							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
dhu	2005/0016290	06/02/2005	deSouza et al.				

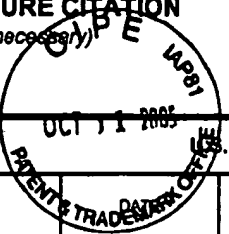
FOREIGN PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)			
dhu			Csepregi, L. et al., Substrate-orientation dependence of the epitaxial regrowth rate from Si-implanted amorphous Si, 49:7 J. Appl. Phys. 3906, 3906-10, (1978);
dhu			6th International Symposium on Semiconductor Wafer Bonding, An investigation into interfacial oxide in direct silicon bonding, (September 2001); and

EXAMINER	DATE CONSIDERED
	03/13/06

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INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)				ATTY DOCKET NO. YOR920030602US1 (17242)		APPLICATION NO. 10/725,850	
				Joel P. de Souza et al.			
				FILING December 2, 2005		GROUP ART 2818	

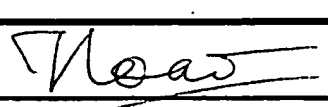


U.S. PATENT DOCUMENTS							
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U.S. PATENT APPLICATION PUBLICATIONS							
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	

FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)			
			Solid State Technology, <i>SOI wafers based on epitaxial technology</i> , (2000), available at http://sst.pennnet.com/articles/article_display.cfm?Section=ARCHI&Feat&ARTICLE_ID75323&KEYWORDS=K%2E%20Sakaguchi&p=5

EXAMINER 	DATE CONSIDERED 03/13/06
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